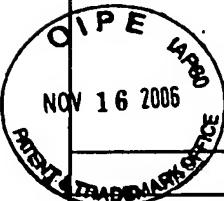


| FORM PTO-1449<br><br><b>INFORMATION DISCLOSURE<br/>STATEMENT BY APPLICANT</b><br>(Use several sheets if necessary) |   | ATTY. DOCKET NO.  |                 | SERIAL NO. |                            |
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|  |   | U 015850-2  |                 | 10/542,123 |                            |
|  |   | APPLICANT   |                 |            |                            |
|  |   | Vladimir Pavlovich POPOV et al.   |                 |            |                            |
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|  |   | December 9, 2005  |                 | 2812       |                            |
|  |   | <b>U.S. PATENT DOCUMENTS</b>  |                 |            |                            |
| EXAMINER INITIALS  | REFERENCE DESIGNATION   | DOCUMENT NUMBER   | DATE            | NAME       | FILING DATE IF APPROPRIATE |
|  | AA  |   |                 |            |                            |
|  | AB  |   |                 |            |                            |
|  | AC  |   |                 |            |                            |
| <b>FOREIGN PATENT DOCUMENTS</b>  |   |   |                 |            |                            |
|  |   | DOCUMENT NUMBER   | DATE            | COUNTRY    | TRANSLATION                |
|  |   |   |                 |            | YES                        |
| .  | AD  |   |                 |            |                            |
| .  | AE  |   |                 |            |                            |
| .  | AF  |   |                 |            |                            |
| <b>OTHER ART</b> (Including Author, Title, Date, Pertinent Dates, Etc.)  |   |   |                 |            |                            |
| /QJ/   | AG  | Rieutord, F. et al. "Dynamics of a Bonding Front" <i>Physical Review Letters</i> (2005) PRL Vol. 94   |                 |            |                            |
| /QJ/   | AH  | Takahagi, T. et al. "Adsorbed Water on a Silicon Wafer Surface Exposed to Atmosphere" <i>Jpn. J. Appl. Phys.</i> (2001) Vol. 40, No. 11, Part 1, pp 6198-6201                           |                 |            |                            |
| /QJ/   | AI  | Gosele, U. et al. "Self-Propagating Room-Temperature Silicon Wafer Bonding in Ultrahigh Vacuum" <i>Appl. Phys. Lett.</i> (1995) Vol. 67, No. 24, pp 3614-3616                           |                 |            |                            |
| /QJ/   | AJ  | Farrens, S.N. et al. "Chemical Free Room Temperature Wafer to Wafer Direct Bonding" <i>J. Electrochem. Soc.</i> (1995) Vol. 142, No. 11, pp 3949-3955                                   |                 |            |                            |
| /QJ/   | AK  | Tong, Q. Y. et al. "Low Vacuum Wafer Bonding" <i>Electrochemical and Solid-State Letters</i> (1998) Vol. 1, No. 1, pp 52-53   |                 |            |                            |
| /QJ/   | AL  | Tong, Q. Y. et al. "Semiconductor Wafer Bonding: Science and Technology" <i>John Wiley &amp; Sons, Inc.</i> (1999) pp 52-53, and pp 122-127   |                 |            |                            |
| /QJ/   | AM  | Esser, R. H. et al. "Improved Low-Temperature Si-Si Hydrophilic Wafer Bonding" <i>Journal of the Electrochemical Society</i> (2003) Vol. 150, No. 3, G228-G231                          |                 |            |                            |
| /QJ/   | AN  | Dragoi, V. et al. "Plasma Activated Wafer Bonding for MEMS" <i>SPIE Proceeding 5836</i> (2005) paper no. 5836-19  |                 |            |                            |
| /QJ/   | AO  | "Long-Term Stability of Vacuum-Encapsulated MEMS Devices Using Eutectic Wafer Bonding" <i>VABOND-Deliverable 6.4 - Technology Guidelines on Vacuum Encapsulation of MEMS</i>            |                 |            |                            |
| /QJ/   | AP  | Zhang, X. et al. "Low-Temperature Wafer Bonding Optimal O <sub>2</sub> Plasma Surface Pretreatment Time" <i>Electrochemical and Solid-State Letters</i> (2004) Vol. 7, No. 8, G172-G174 |                 |            |                            |
| EXAMINER   | /Quovaunda Jefferson/   |   | DATE CONSIDERED | 06/19/2007 |                            |
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